

Claims

1. An electrostatic chuck for a substrate stage, characterized in that a plurality of electrodes are disposed in parallel.
2. An electrostatic chuck for a substrate stage according to Claim 1, wherein said electrodes are electrodes different in width.
3. An electrostatic chuck for a substrate stage according to Claim 1, wherein said electrodes are disposed with a predetermined clearance from one another.
4. An electrostatic chuck for a substrate stage according to Claim 1, wherein said electrodes are disposed along an edge portion of a substrate to be treated.
5. An electrostatic chuck for a substrate stage according to Claim 1, wherein wiring to said electrodes can be changed over to mono-pole or bi-pole.
6. An electrostatic chuck for a substrate stage according to Claim 1, wherein said electrodes are made of bar-like base materials.
7. An electrostatic chuck for a substrate stage according to Claim 6, wherein highly pure ceramics is thermally sprayed on surfaces of said base materials to form a thermally sprayed

film.

8. An electrostatic chuck for a substrate stage according to Claim 6, wherein sectional shapes of said base materials are squares.

9. An electrostatic chuck for a substrate stage according to Claim 6, wherein sectional shapes of said base materials are wide rectangles.

10. An electrostatic chuck for a substrate stage according to Claim 6, wherein sectional shapes of said base materials are stepped shapes.

11. An electrostatic chuck for a substrate stage according to Claim 6, wherein sectional shapes of said base materials are arranged like roofing tiles each of which has a curved convex portion in one side and a curved concave portion in the other side, and said electrodes are disposed with a predetermined clearance between said convex portion of one electrode and said concave portion of another adjacent electrode.

12. An electrostatic chuck for a substrate stage according to Claim 6, wherein said base materials are made of highly pure isotropic graphite.

13. An electrode of an electrostatic chuck for a substrate stage, characterized in that highly pure ceramics is thermally

sprayed on surfaces of bar-like base materials to form a thermally sprayed film.

14. An electrode according to Claim 13, wherein sectional shapes of said base materials are squares.

15. An electrode according to Claim 13, wherein sectional shapes of said base materials are wide rectangles.

16. An electrode according to Claim 13, wherein sectional shapes of said base materials are stepped shapes.

17. An electrode according to Claim 13, wherein sectional shapes of said base materials are shapes like roofing tiles each of which has a curved convex portion in one side and a curved concave portion in the other side.

18. An electrode according to Claim 13, wherein said base materials are made of highly pure isotropic graphite.

19. A treating system having an electrostatic chuck for a substrate stage, wherein a plurality of electrodes are disposed in parallel in said electrostatic chuck

20. A treating system having an electrostatic chuck for a substrate stage according to Claim 19, wherein said electrodes are electrodes different in width.

21. A treating system having an electrostatic chuck for a substrate stage according to Claim 19, wherein said electrodes

are disposed with a predetermined clearance from one another.

22. A treating system having an electrostatic chuck for a substrate stage according to Claim 19, wherein said electrodes are disposed along an edge portion of a substrate to be treated.

23. A treating system having an electrostatic chuck for a substrate stage according to Claim 19, wherein wiring to said electrodes can be changed over to mono-pole or bi-pole.

24. A treating system having an electrostatic chuck for a substrate stage according to Claim 19, wherein said electrodes are made of bar-like base materials.

25. A treating system having an electrostatic chuck for a substrate stage according to Claim 24, wherein highly pure ceramics is thermally sprayed on surfaces of said base materials to form a thermally sprayed film.

26. A treating system having an electrostatic chuck for a substrate stage according to Claim 24, wherein sectional shapes of said base materials are squares.

27. A treating system having an electrostatic chuck for a substrate stage according to Claim 24, wherein sectional shapes of said base materials are wide rectangles.

28. A treating system having an electrostatic chuck for a substrate stage according to Claim 24, wherein sectional shapes

of said base materials are stepped shapes.

29. A treating system having an electrostatic chuck for a substrate stage according to Claim 24, wherein sectional shapes of said base materials are arranged like roofing tiles each of which has a curved convex portion in one side and a curved concave portion in the other side, and said electrodes are disposed with a predetermined clearance between said convex portion of one electrode and said concave portion of another adjacent electrode.

30. A treating system having an electrostatic chuck for a substrate stage according to Claim 24, wherein said base materials are made of highly pure isotropic graphite.

TABLE 1

A	B	mono-pole/bi-pole
+	+	+ for mono-pole
-	-	- for mono-pole
+	-	bi-pole
-	+	
+	ground	
-	ground	
ground	+	
ground	-	